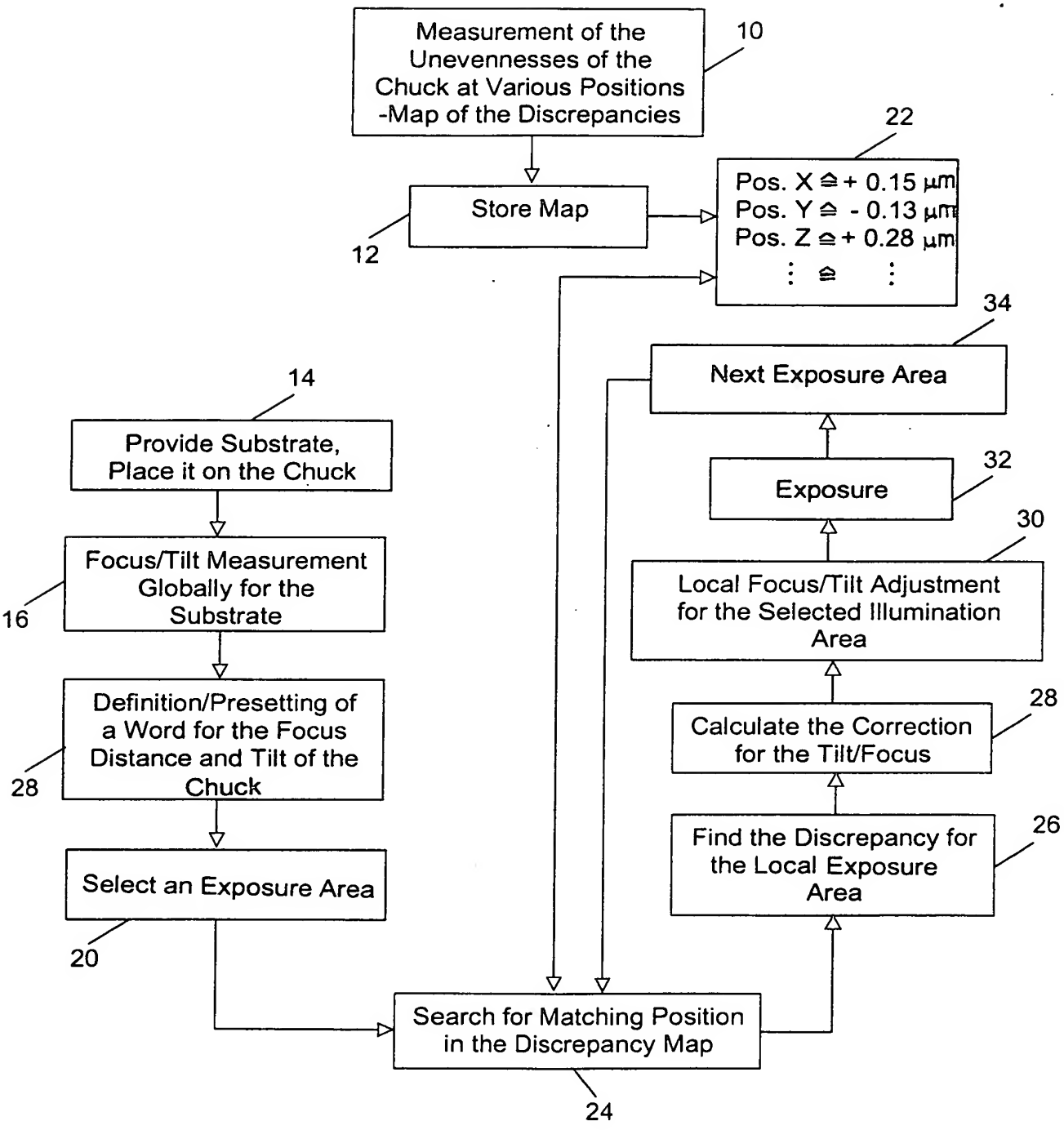
Measurement of the Unevennesses of the Chuck at Various Positions -Map of the Discrepancies
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Pos. X ≙ + 0.15 µm
Pos. Y ≙ - 0.13 µm
Pos. Z ≙ + 0.28 µm
⋮ ≙ ⋮
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